

IN THE CLAIMS

1. (original) A method for analyzing defect information on a substrate, the method comprising the steps of:
 logically dividing the substrate into zones,
 detecting defects on the substrate to produce the defect information,
 5 analyzing the defect information from the substrate on a zone by zone basis to
 produce defect level classifications for the defects within each zone, and
 analyzing the zonal defect level classifications according to at least one analysis
 method.
2. (original) The method of claim 1, wherein the defect level classifications are selected from a group of defect level classifications that is specified by a recipe.
3. (original) The method of claim 1, wherein the at least one analysis method includes at least one of zonal defect distribution, automatic defect classification, spatial signature analysis, and excursion detection.
4. (original) The method of claim 1, wherein the defect level classifications include at least one of individual defect, defect cluster, and spatial signature analysis signature.
5. (original) The method of claim 1, wherein the defect information is logically divided into configurable zones after the defects on the substrate have been detected.
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